

## **AMENDMENTS TO THE CLAIMS**

The following listing of claims will replace all prior versions, and listings, of claims in the application:

### **Listing of Claims:**

Claim 1 (currently amended): An apparatus for testing a substrate by irradiation of electron beam, comprising:

a scan parameter calculating unit for calculating a stage speed and an irradiating position of electron beam on the basis of an array of measurement points in a unit area ~~set for each~~associated with a substrate species, which is an object to be tested, the stage speed being a speed of a stage for supporting and moving the substrate disposed thereon;

a species information input unit whereby information regarding the substrate species is collected and provided to said scan parameter calculating unit;

a stage control unit for controlling the movement of the stage; and  
an electron beam control unit for controlling the irradiating position of electron beam,

wherein said stage control unit drives the stage at a calculated stage speed, and said electron beam control unit controls a calculated irradiating position of electron beam in synchronism with the movement of the stage.

Claim 2 (currently amended): The substrate testing apparatus according to claim 1,

further comprising:

a measurement point acquiring unit for acquiring the array of measurement points in the unit area ~~on the basis of~~based upon the substrate species information ~~set for each substrate species~~collected by said species information input unit and for providing the array of measurement points to said scan parameter calculating unit.

Claim 3 (currently amended): The substrate testing apparatus according to claim 2, wherein the substrate species information is ~~the array of measurement points in the unit area or~~ the substrate species for designating the type of substrate, and said measurement point acquiring unit acquires the array of measurement points by ~~directly inputting it, or by~~ inputting the substrate species and referring to the correspondence relation data between the substrate species and the array of measurement points to acquire the corresponding array of measurement points.

Claim 4 (currently amended): A method for testing a substrate by irradiation of electron beam, comprising:

collecting information regarding a particular substrate species to which the substrate belongs;

calculating a stage speed and an irradiating position of electron beam on the basis of an array of measurement points in a unit area which is set for each substrate species ~~which is an object to be tested~~, the stage speed being a speed of a stage for supporting and moving the substrate disposed thereon;

driving the stage at a calculated stage speed;

and controlling a calculated irradiating position of electron beam in

synchronism with the movement of said stage.

Claim 5 (currently amended): The substrate testing method according to claim 4, further comprising:

acquiring the array of measurement points in the unit area based upon~~on the~~  
~~basis of~~ the substrate species information collected regarding the particular  
substrate species set for each substrate species.

Claim 6 (currently amended): The substrate testing method according to claim 5, wherein the acquiring step includes acquiring the array of measurement points ~~by directly inputting it, or~~ by inputting the substrate species and referring to the correspondence relation data between the substrate species and the array of measurement points to acquire the corresponding array of measurement points.

Claim 7 (new): The substrate testing apparatus according to claim 2 wherein the substrate species information is stored on a recording medium provided for the substrate.

Claim 8 (new): The substrate testing apparatus according to claim 7 wherein the recording medium is selected from a group consisting of a bar code, a magnetic recording and an IC chip.

Claim 9 (new): The substrate testing apparatus according to claim 1, wherein the substrate species information is the substrate species for designating the type of

substrate, and said measurement point acquiring unit acquires the array of measurement points by inputting the substrate species and referring to the correspondence relation data between the substrate species and the array of measurement points to acquire the corresponding array of measurement points.

Claim 10 (new): The substrate testing method according to claim 5, wherein the acquiring step includes acquiring the array of measurement points by directly inputting the array of measurement points.

Claim 11 (new): The substrate testing apparatus according to claim 2, wherein the substrate species information is stored on a recording medium provided on one of the substrate, a conveyor for conveying the substrate, and a conveyor controller.

Claim 12 (new): The substrate testing apparatus according to claim 11, wherein the recording medium is selected from a group consisting of a bar code, a magnetic recording and an IC chip.

Claim 13 (new): The substrate testing apparatus according to claim 2, wherein the substrate species information is the array of measurement points in the unit area, and said measurement point acquiring unit acquires the array of measurement points by directly inputting the array of measurement points.